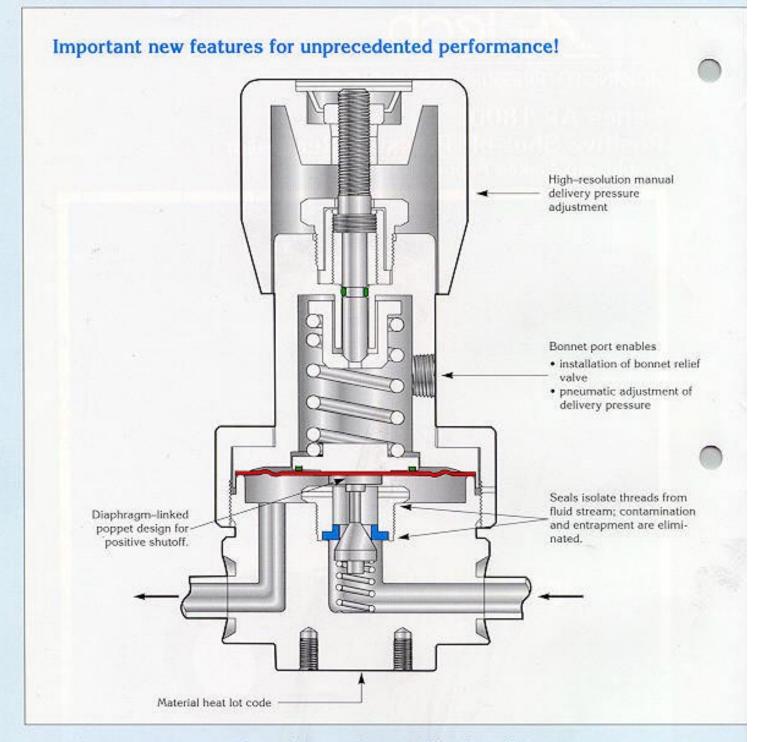


ADVANCED PRESSURE TECHNOLOGY

Series AP 1800 Positive Shut-off Pressure Regulator Diaphragm-Linked Poppet^{IM}



- High flow rate applications for low delivery pressure
- · Contaminant free
- 15μ in. surface finish
 (10, 7 and 5μ in. optional)
- SS 316L construction
- Vacuum to 300 psig (21 bar)
- Flow rates to 400 slpm (14 scfm)
- Cleaned, assembled and packaged for high purity semiconductor applications



A modern pressure regulator for modern applications!

AP Tech Series AP 1800 Line Pressure Regulators incorporate many new features to eliminate particle shedding and chemical contamination problems which plague users of conventional line pressure regulators. Specifically engineered for use in semiconductor fab locations and other sensitive applications, they are precision manufactured from stainless steel 316 L, and are suitable for use with corrosive and noncorrosive gases.

Particle generation is a thing of the past, thanks to AP Tech's exclusive diaphragm – linked poppet and seat design. Seals isolate all threads from the gas stream. These features make Series AP 1800 positive shutoff line pressure regulators best for applications that demand the ultimate in gas stream purity and safety.

Engineering data - Series AP 1800 Pressure Regulator

Operating parameters

Source pressure	vacuum to 300 psig (21 bar)					
Delivery pressure (AP 1802)	1 to 30 psig (0.07 to 2 bar)					
Delivery pressure (AP 1806)	1 to 60 psig (0.07 to 4 bar)					
Delivery pressure (AP 1810)	2 to 100 psig (0.14 to 7 bar)					
Proof pressure	500 psig (35 bar)					
Burst pressure	4000 psig (276 bar)					

Other parameters

Inlet and outlet connectors	14, 16 or 12 inch face seal, 16 or 12 inch tube weld, 14 or 16 inch NPT						
Actuation/relief port	36 inch NPT						
Flow coefficient (Cv)	0.36						
Internal volume	0.65 in ³ (10.6 cm ³)						
Operating temperature	-40" to +160"F (-40" to +71"C)						
Surface finish	10–15μin (0.25–0.4μm) standard 10μln. (.25μm); 7μin. (.18μm); 5μin. (.13μm) optional						
Inboard leakage	2 x 10 ⁻¹⁰ sccs						
Outboard leakage	2 x 10° sccs He at 300 psig inlet pressure						
Leakage across seat	4 x 10° sccs He at 100 psig inlet pressure						
Installation	surface or panel (optional)						
Delivery pressure rise	6 psi per 100 psig inlet pressure drop						

Materials

Wetted Parts					
Body and diaphragm	stainless steel 316 L VAR				
Finish	electropolished and passivated				
Seat	PCTFE (Vespel* optional)				
Non-wetted Parts					
Bonnet, cap, plate	nickel-plated brass				
O-ring	Viton®				
Stem	brass				

All specifications subject to change without notice

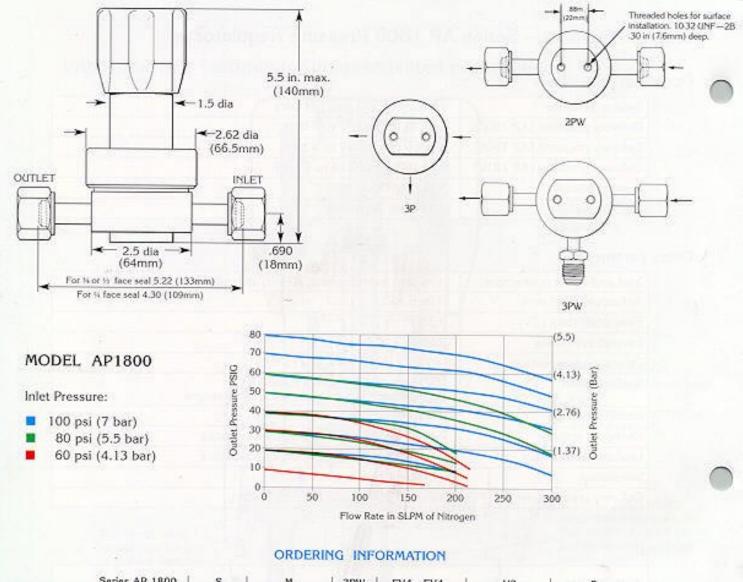
Vespel® DuPont

Viton® DuPont

Cleaning and packaging

Cleaning is a multi-step process performed in a Class 100 clean room. Parts are ultrasonically cleaned with a wetting agent initially and then progressively with hot and cold DI water. Cleaned parts are then blown dry with ultra pure nitrogen prior to being baked completely dry in a nitrogen atmosphere.

Each regulator is then individually assembled, pressure tested, functionally tested and helium leak tested. Labels, including a unique serial number, are installed prior to products being double packaged under ultra pure nitrogen.



Series AP 1800	S Material	M Surface Finish Options	3PW Ports	Conne	- FV4 ections Outlet	V3 Gauges*	P Options
AP1802 = 1-30 psi (.07 to 2 bar) AP1806 = 2-60 psi (.14 to 4 bar) AP1810 = 2-100 psi (.14 to 7 bar)		Options	EON	met	Outlet	Delivery	P = Panel installation ring ** VS = Vespel seat
S = Stainless steel M = 10μ in, Ra V = 7μ in, Ra X = 5μ in, Ra						0 = No gaug V3 = 30-0-30- L = 30-0-60	psi/bar 2 = 0-200 psi/bar
3P = 3 ports (1/4 or 1/8 NPTF) 2PW = 2 ports butt weld 3PW = 3 ports butt weld 4PW = 4 ports butt weld				FV4 = 1/4 inch face-seal female MV4 = 1/4 inch face-seal male FV6 = 3/8 inch face-seal female MV6 = 3/8 inch face-seal male MV6 = 3/8 inch face-seal male TV6 = 3/8 inch tube weld stub FV8 = 1/2 inch face-seal female TV8 = 1/2 inch face-seal female			

Products by AP Tech

AP Tech manufactures a wide array of products exclusively for the semiconductor industry. Pressure regulators, valves, check valves and a variety of flow devices are available for applications ranging from the source cylinder cabinet, bulk delivery systems through point of use including VMB distribution boxes and process tool gas trays. Products can be tailored for specific needs with custom fittings, dimensions, porting or testing with an option of multiport, monoblock and surface mount configurations.